

# BEST AVAILABLE COPY

## Notice of References Cited

Application No.

08/903486

Applicant(s)

Forbes

Examiner

William Mintel

Group Art Unit

2811

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### U.S. PATENT DOCUMENTS

*		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS
X	A	5369040	11/29/94	Halvi's et al.	437	3
	B					
	C					
	D					
	E					
	F					
	G					
	H					
	I					
	J					
	K					
	L					
	M					

### FOREIGN PATENT DOCUMENTS

Karuyankumaaru

*		DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
X	N	07-115191	5/2/95	Japan	Karuyankumaaru		
X	O	63-289960	11/28/88	Japan	Ito		
	P						
	Q						
	R						
	S						
	T						

### NON-PATENT DOCUMENTS

*		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
	U	Demichelis et al., "Influence of Doping on the Structural and Optoelectronic Properties of Amorphous and Microcrystalline Silicon Carbide", <u>J. Appl. Phys.</u> 72 (4) 15 August 1992, pp. 1327-1333.	August 15, 1992
	W		
	X		

\* A copy of this reference is not being furnished with this Office action.  
(See Manual of Patent Examining Procedure, Section 707.05(a).)